

Hysteresis Modeling in a Piezoelectric Nanopositioner Stage

A. Telba and Wahied G. Ali

Abstract—Piezoelectric materials have many advantages, such as: high stiffness, a high frequency response, and high resolution. It has been widely used in reducing vibration system, but hysteresis confines its use. This paper aims to develop the hysteresis model for a single axis piezoelectric nanopositioner stage at different operating points. The adopted methodology is to compare between the analytical model using MATLAB and the real time results using LabVIEW. The experimental results for real measurements had been acquired for the piezoelectric nanopositioner stage using data acquisition system from National Instruments. The experimental setup is described and output results for simulation and real time measurements are compared to validate the adopted approach.

Index Terms—Piezoelectric Materials, Actuators, Hysteresis, Modeling.

I. INTRODUCTION

HYSTERESIS is a nonlinear phenomenon occurring in many engineering devices such as the micro and nano piezoelectric actuators (PZA), the shape memory alloys (SMA), and the ferromagnetic elements [1-4]. A system with hysteresis is usually difficult to describe accurately and may result in unstable behaviors if not controlled appropriately. Therefore, an accurate model of hysteresis is critical in order to develop suitable control algorithms or applications with these systems [5]. Several models have been developed to characterize systems with hysteresis and the classical Preisach model (CPM) has been known as the most familiar one to characterize hysteresis behaviors [6]; this model can be further represented by an infinite but countable first order [7]. Modeling, simulations and experimental work of piezoelectric nanopositioning actuator had been done. Hysteresis is one of the most effects in nanopositioning system; in this case the PI 754 nanopositioning actuator system is used. Classical actuators (electromagnetic, hydraulic and pneumatic) are the most used in the industry; new technologies based on different physical principles are being developed. In applications where the size of the actuator has to be miniaturized, or

where fast response and high resolution are needed, the classical actuators fail to respond appropriately. For this reason, non-classical technologies are becoming more relevant. Among them, the piezoelectric actuators are proving to be a reliable solution for many engineering applications, ranging from micro and nano positioning applications (machine tools, optic devices or modern microscopes biomedical, nano-robots, and automotive).

The paper is organized as follows: Section II describes the hysteresis behavior in piezoelectric materials. Section III presents the experimental results. Section IV concludes the paper and highlights the main points.

II. PIZOELECTRIC MATERIALS HYSTERESIS

Piezoelectric materials' hysteresis is the different displacement behavior at the same voltage values either ascending or descending. As shown in figure 1, ΔH is maximum displacement different. ΔH reflects piezoelectric materials' hysteresis [8].

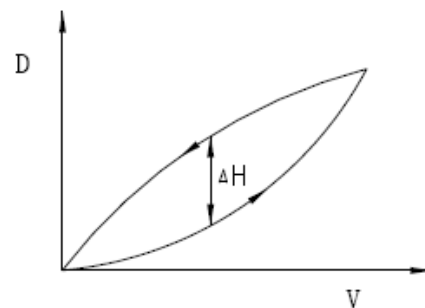


Fig. 1. Piezoelectric materials' hysteresis [8].

Many researchers have been interested with hysteresis behavior in piezoelectric materials. In general, hysteresis' research has two methods: the former is to find the hysteresis reason of piezoelectric materials, such as domain model in [9-10]; the latter is to consider hysteresis as a black box and identify the hysteresis characteristics using a numerical analysis approach, such as Preisach model in [11], slide model in [12], and neural networks model in [13]. Discrete Preisach model using numerical is shown in figure 2. In our case study increasing the number of iterations, the model will present the real model, the 3rd order polynomial used to solve equations of (1) and (2).

Manuscript received January 12, 2011; revised April 8, 2011. This work was supported in part by supported by NPST program by King Saud University, Project number "08-NAN388-02".

A. Telba is with the Electrical Engineering Department, College of Engineering, King Saud University, Riyadh, Saudi Arabia (phone: +96614678800, fax: +96614676757, email: atelba@ksu.edu.sa).

Wahied G. Ali is with the Electrical Engineering Department, College of Engineering, King Saud University, (email: wahied@ksu.edu.sa).

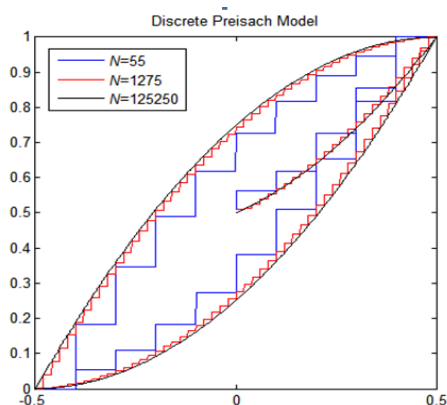


Fig .2. Discrete Preisach model using numerical analysis [6].

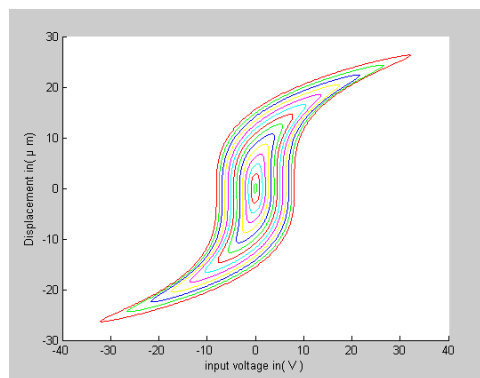


Fig. 4. Analytical model of hysteresis simulated by MATLAB.

$$F0(x) = a0 + a1 * x + a2 * x^2 + a3 * x^3 \quad (1)$$

$$G0(x) = b0 + b1 * x + b2 * x^2 + b3 * x^3 \quad (2)$$

In fig 3, horizontal axis denotes apply voltage, vertical axis denotes displacement of piezoelectric actuator in micrometers. When voltage increased, the displacement increased related to the input voltage.

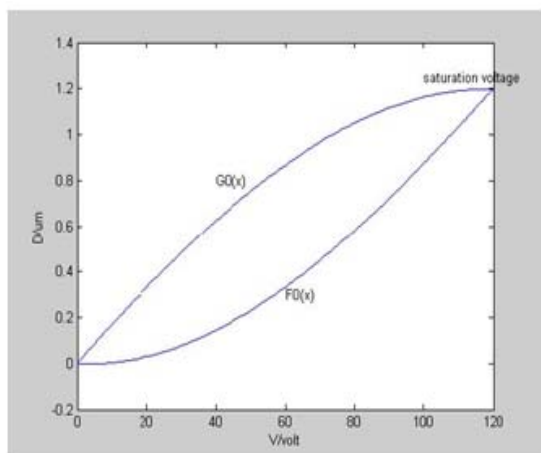


Fig .3. Model using numerical analysis [8].

The maximum displacement is regarded to 100V in nanpositioning; this voltage is named saturation voltage. When voltage descends from saturation voltage to zero, the displacement descends. The displacement of descending is different than the displacement of ascending. The two curve don't change, and are named limit G0(x) and F0(x) [2]. In order to describe the limit curves, using least quadric (LQ) fit the data. From simulation results, it has been noticed that the two curve G0(x) and F0(x) come out as same as before then polynomial degree increase, the model's precision improve. So we use n=3, and fit it using equation (1) and (2).

III. EXPERIMENTAL RESULTS

In this section, we used the proposed real-time experiments. Figure 5 shows the experimental setup which consists of: Industrial PC from National Instruments (PXI system) with an installed LabVIEW software, data acquisition card (DAQ NI 6361), single axis nanopositioner PI-752.21C with a displacement measurement using capacitor, signal conditioning circuit for the displacement measurements, and a piezoelectric power amplifier.

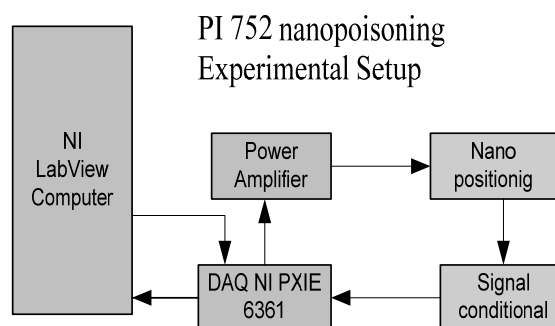


Fig. 5. Experimental setup.

Fig. 6 represents the LabVIEW code to acquire the hysteresis behavior for PI-752.21C nanopositioner. DAQ assistant VIs is used to interface the program with real time measurements.

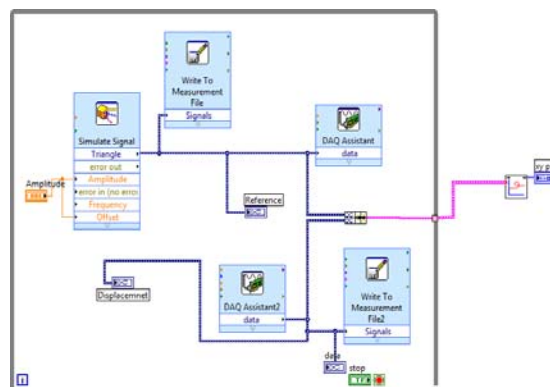


Fig. 6. LabVIEW Code for real time measurements.

The real time displacement is recorded in both text file and real time output as shown in figure 7 and measured both input voltage in x axis and displacement of the nanopositioner in y axis. The figure to the right up corner is the relation of traveling in both ascending and descending of the piezoelectric nanopositioner.

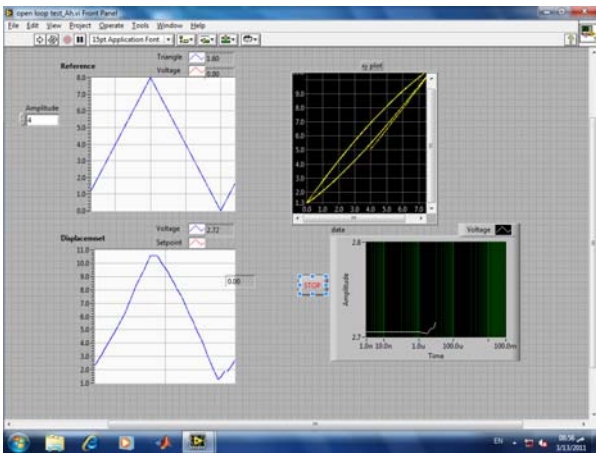


Fig.7. Real time measurement of piezoelectric nanopositioner.

In the above figure, the left up corner refers to the input voltage is triangular wave with peak of 4V and using frequency of 10Hz for real time testing of the simulated signal while the left down corner refers to displacement of Nano-Positioning Piezoelectric while the right up is referred to the Hysteresis curve from real time at input 4V peak triangular wave. In the experimental work using different peak voltage (1V, 2V, 3V, V4, 5V) with same frequency of 10Hz, the Hysteresis Measured in real image as shown in fig 7 and text file and plotted using MATLAB.

IV. CONCLUSION

This paper investigated the hysteresis modeling for a single axis nanopositioner stage. The adopted approach is to acquire the real time characteristics experimentally; then store it in a text file and redraw it using MATLAB. The simulated model in MATLAB is identified using a 3 rd order polynomial. The obtained model is approved by comparing its behavior to that obtained by real time measurements, and the identification error can be measured in LabVIEW program. This error can decrease hysteresis effectively in integrating with speed of the Nanopositioning stage. Real time measurement is acquired and the hysteresis at different input voltage is measured.

REFERENCES

[1] D. Hughes and J. T.Wen, "Preisach modeling of piezoceramic and shape memory alloy hysteresis," IEEE Conference on Control Applications - Proceedings, pp. 1086-1091, 1995.
 [2] B. N. Agrawal, M. A. Elshafei, and G. Song, "Adaptive antenna shape control using piezoelectric actuators," Act. Astronaut., vol. 40, no. 11, pp. 821-826, 1997.
 [3] P. Mayhan, K. Srinivasan, S.Watechagit, and G.Washington, "Dynamic modeling and controller design for a piezoelectric actuation system used for machine tool control," Journal of

Intelligent Material Systems and Structures, vol. 11, no. 10, pp. 771-780, 2000.
 [4] Slocum and Alexander H., Precision machine design, Englewood Cliffs, NJ: Prentice-Hall, 1992.
 [5] D. Croft, G. Shed, and S. Devasia, "Creep, hysteresis, and vibration compensation for piezoactuators: Atomic force microscopy application," ASME Journal of Dynamic Systems, Measurement, and Control, vol. 123, no. 1, pp. 35-43, 2001.
 [6] I. D. Mayergoz, Mathematical Models of Hysteresis, New York: Springer-Verlag, 1991.
 [7] Van-Tsai Liu, Wei-Chih Yang and Home-Young Wing "Realization of Preisach Model Using Adaptive Polynomial Approximation Method" . 2010 5th IEEE Conference on Industrial Electronics and Applications
 [8] Li Zhan-hui, Wu Yun-xin, Deng Xi-shu "Modeling and Compensating of Piezoelectric Actuator Hysteresis in Photolithography "IEEE Proceedings of HDP'07 2007.
 [9] G Le Rhun, I Vrejoiu, L Pintilie etc. G'osele.Increased ferroelastic domain mobility in ferroelectric thin films and itsin nano-patterned capacitors." Nanotechnology 17 (2006) 3154-3159 .
 [10] Mayergoz, G.Bertotti, Elsevier , The Science of Hysteresis, Volume 3; I. (2005):357-362
 [11] Declan Hughes, John T Wen. Preisach modeling of piezoceramic and shape memory alloy hysteresis. Smart Mater. Struct. 6 (1997) 287-300
 [12] Shuanghe Yu, Bijan Shirinzadeh, Gursel Alici etc.Sliding Mode Control of a Piezoelectric Actuator with Neural Network Compensating Rate-Dependent Hysteresis. International Conference on Robotics and Automation Barcelona, Spain, April 2005:3641-3646
 [13] Péter BERÉNYI, Gábor HORVÁTH, Vincent LAMPAERT etc. non-local hysteresis function identification and compensation with neural networks. PERIODICA POLYTECHNICA SER. EL. ENG. VOL. 47, NO. 3-4, PP. 253-267 (2003)
 [14] Deng xi-shu, Wu yun-xin.simulation study on precision vibration reduction system for working stage of lithography.2005 6th international conference on electronic.